

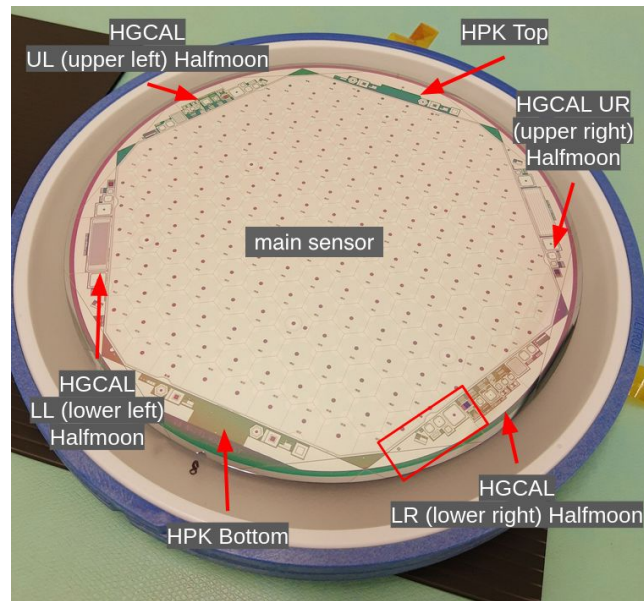
# Comparison of X-ray radiation damage for different oxide types in HGCAL silicon sensors prototypes

Pablo Álvarez Domínguez (ETH Zürich, CERN),  
Matteo Defranchis (CERN), Leena Diehl (CERN)

on behalf of the CMS collaboration

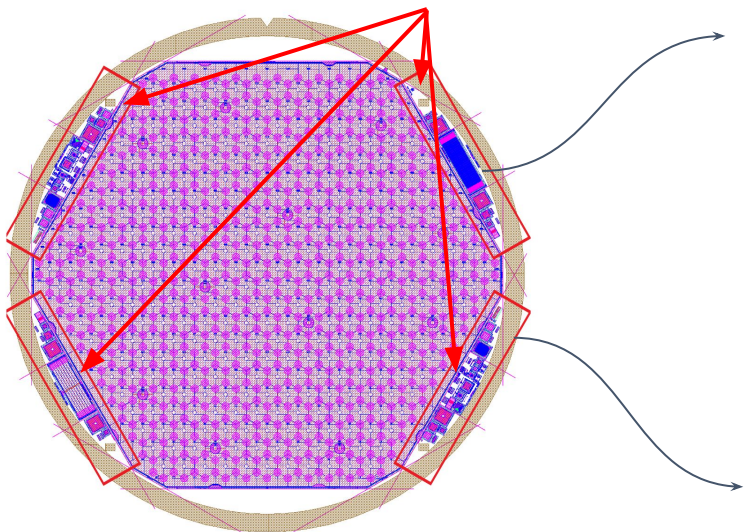


- HGCAL silicon sensors produced by Hamamatsu (HPK)
  - First 8-inch p-type sensors used in a particle detector
  - Radiation hardness qualification needed for bulk and **oxide**
    - Oxide radiation hardness important for cell isolation
  
- In the 8-inch prototype phase (2018–2022), HPK provided amongst others **10 oxide variants**
  - First prototypes had **-5V** flat band voltage ( $V_{fb}$ )
  - HGCAL wished to mimik **CMS outer tracker** sensors which are well established in terms of radiation hardness, with  $V_{fb} = -2V$
  - HGCAL production started using so-called **Type C** with  $V_{fb} = -2V$ , (best performance among provided oxide variants)
  - In parallel to production start in 2023, HPK proposed **Type C'** (more similar to tracker sensors, also in terms of p-stop resistance)
  - **Fast track qualification** needed of new oxide variant to be relevant for production

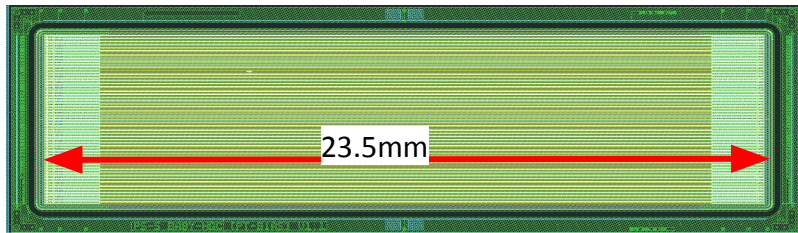


## HGCAL sensor

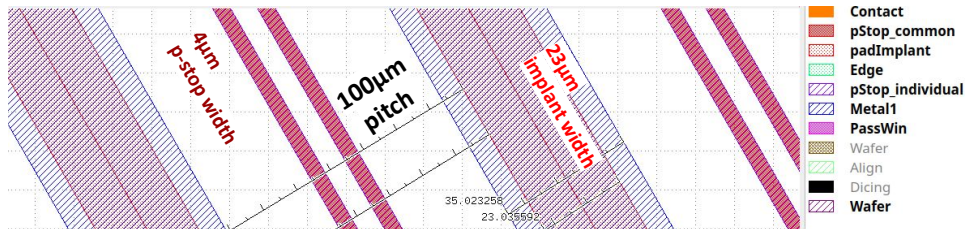
Half moons with test structures



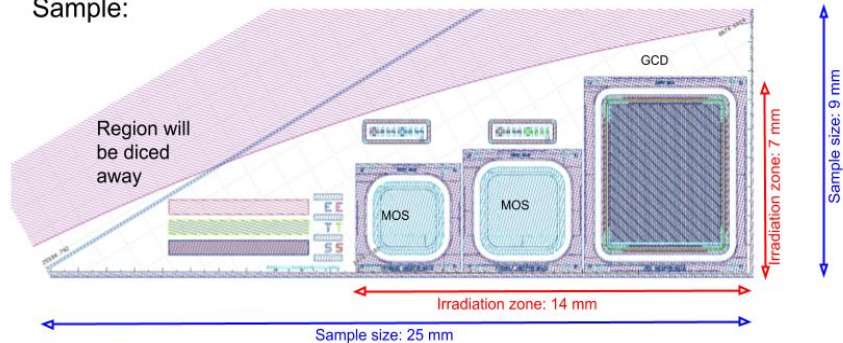
60 strips



Strip sensors



Sample:



MOS

## HGICAL 8-inch:

	Vfb	p-stop	oxide quality improvement	p-stop concentration	comment
A	-5V	common	STD	STD	not improved Vfb & STD condition (for ref.)
B	-2V	common	STD	STD	improved Vfb with special masking method
C	-2V	common	thermal condition change	STD	(for ref.) production condition
C'	-2V	common	thermal condition change	STD*	more close to 6" line than type C
D	-2V	common	combination of B and C	STD	CMS required condition
E1	-2V	common	thermal condition change	x2.5	combination C and p-stop concentration
E2	-2V	common	thermal condition change	x5.0	

\*MOSFET measurements indicate higher p-stop concentration in Type C' than in Type C

## HGICAL 8-inch:

- 300 $\mu$ m float zone (FZ),  $V_{dep} = \sim 270V$

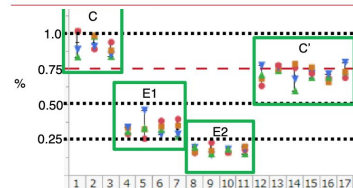
## HGICAL 6-inch:

- 320 $\mu$ m physical thickness, 290 $\mu$ m active thickness, deep diffused float zone (dd-FZ)

## CMS outer tracker (6-inch):

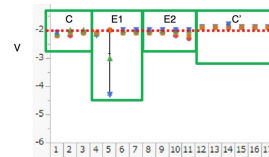
- Sample from PS-s wafer from the pre-production (series S15569-01)
- 320 $\mu$ m physical thickness, 290 $\mu$ m active thickness, deep diffused float zone (dd-FZ)

P-stop resistance for each condition



Type C' is about 20% lower than type C.

Flatband voltage for each condition



The flatband voltage of type C' is nearer to 0V than that of type C. However, there is no difference and oxide layer quality is almost same we think. Productivity for type C' is also same level as type C.

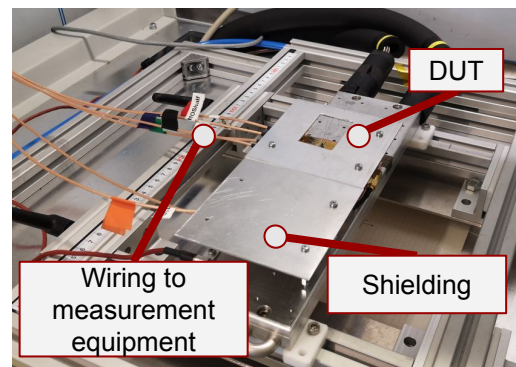
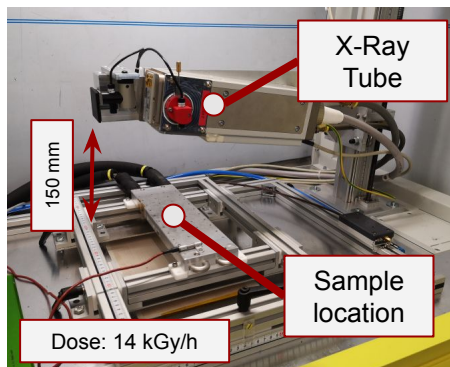
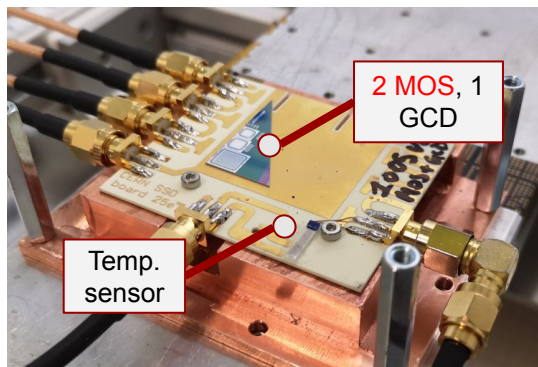
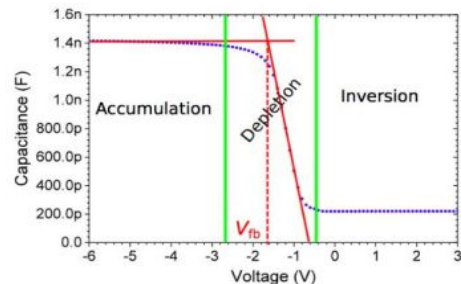
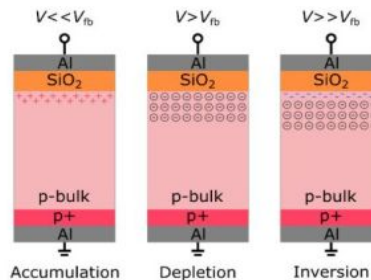
- Effect of **trapped charge**:

- Increase in  $V_{\text{flatband}}$  in MOS
- Increase in **surface current** in GCD

- Measurement **procedure**:

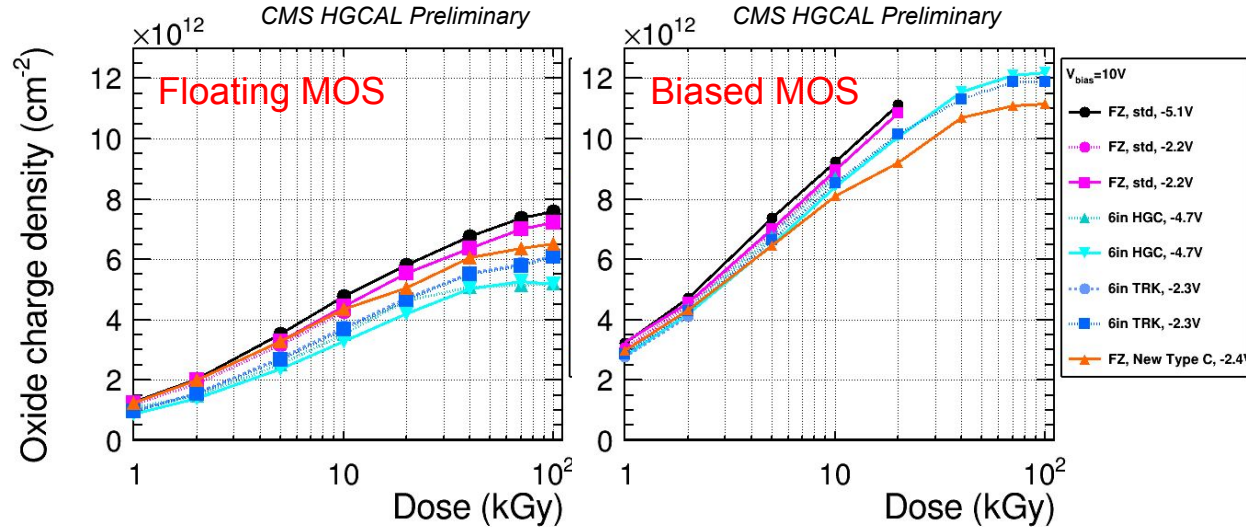
- X-ray irradiation and in-situ measurements at **<1%** relative humidity and **-20 °C**  
→ **Crucial to control annealing**
- Dose rate = **14 kGy/h**
- One of the two MOS biased with **+10 V** in order to study the radiation damage in the presence of an **electric field**

MOS



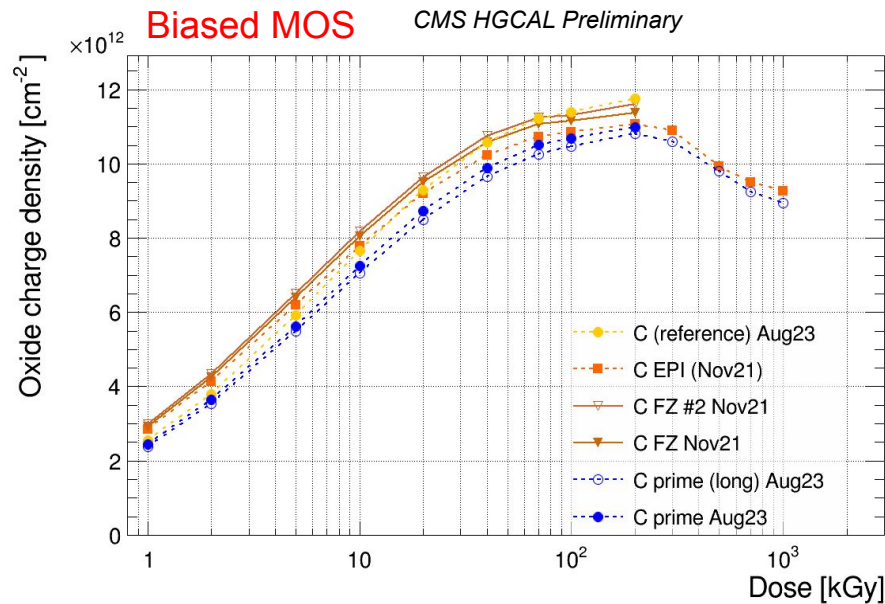
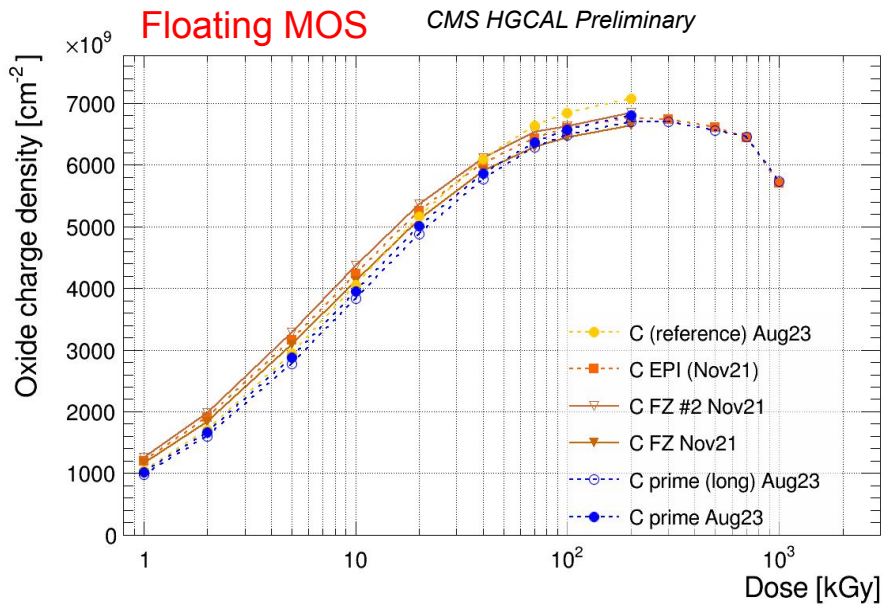
- Convert  $V_{\text{flatband}}$  into oxide charge density  

$$N_{\text{oxide}} = \frac{C_{\text{oxide}}}{qA_{\text{gate}}} (\phi_{\text{ms}} - V_{\text{FB}})$$
- **Type C** compared to **HGCAL 6"** prototypes and **CMS outer tracker** (benchmarks), obtained with the same procedure



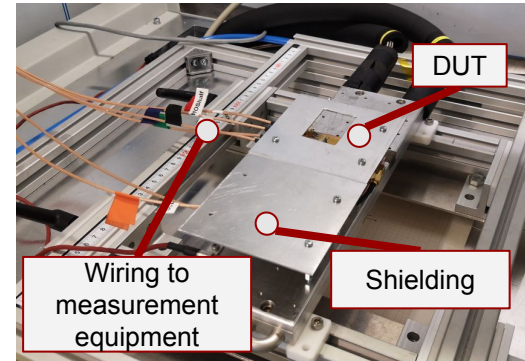
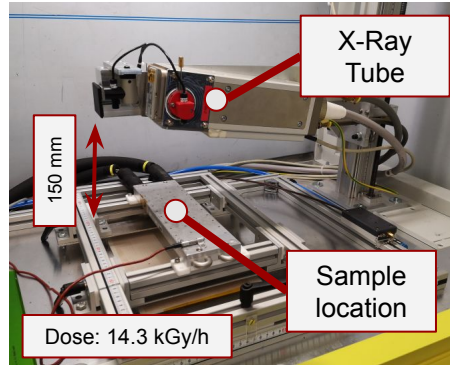
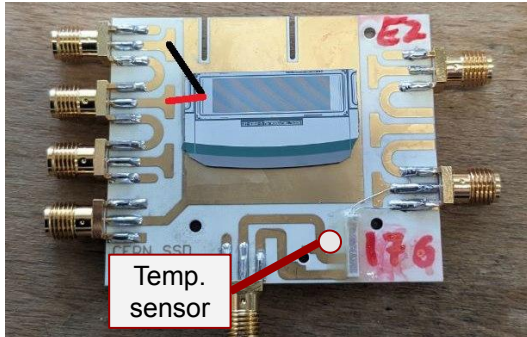
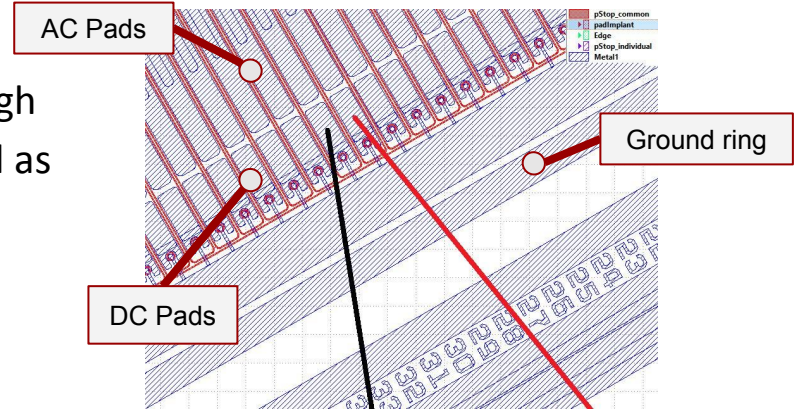
- Comparable performance and trend in the absence of electric field
- **Type C** performs better in the presence of an electric field

-> In both cases, better performance compared to  $V_{\text{fb}} = -5\text{V}$  prototypes



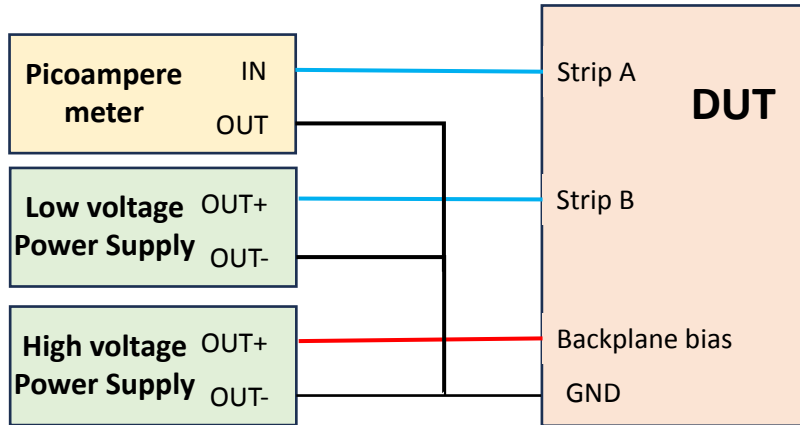
- Differences between **Type C'** and **Type C** within the experimental resolution (around 5%)
- This motivates the need to perform complementary studies with **micro-strips**

- Wire bonding of 2 neighbour strips
- Strips biased via bias ring, connected via punch-through
- X-ray irradiation and in-situ measurements performed as for MOS
- Measurements
  - **Interstrip resistance** and capacitance

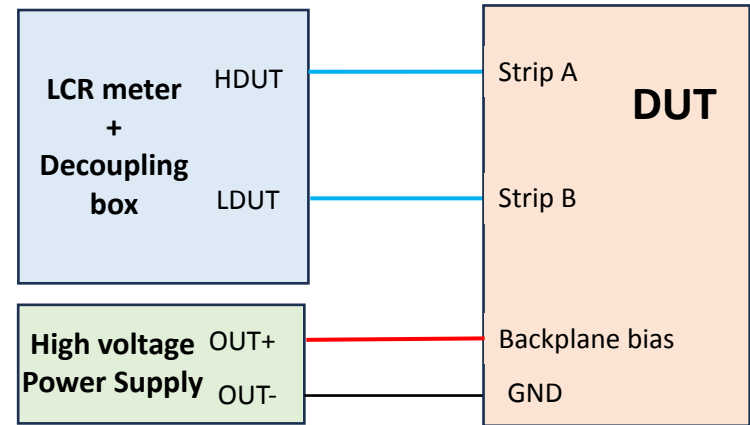


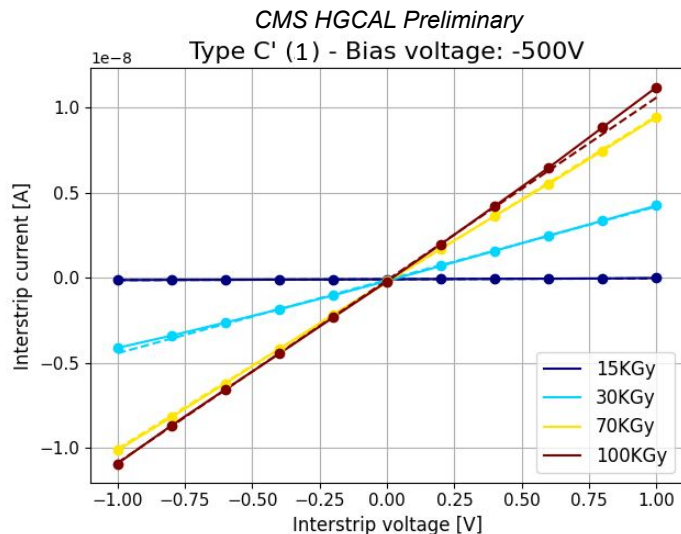
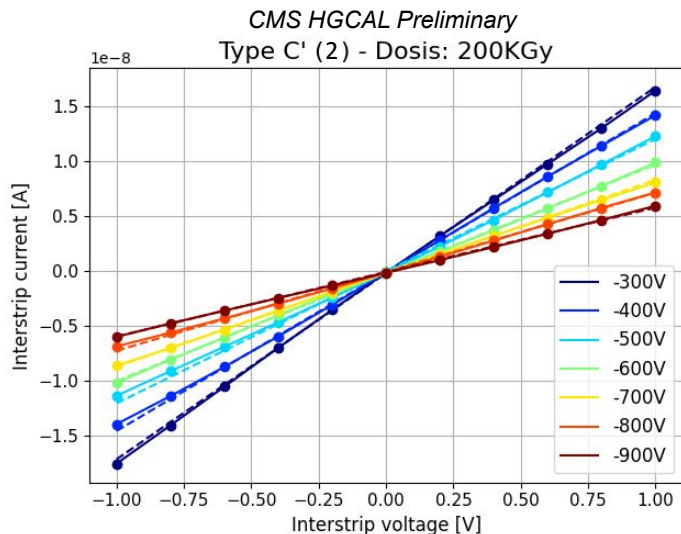


## Inter-strip resistance



## Inter-strip capacitance



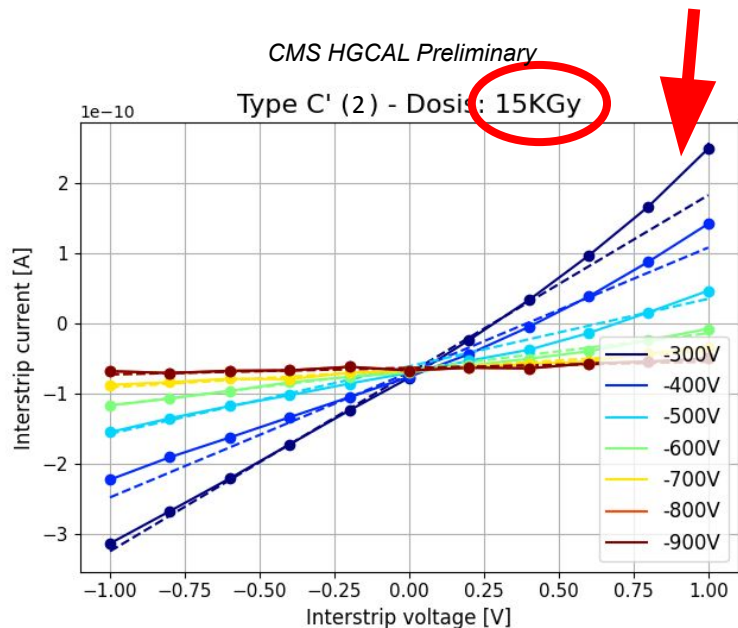


**Linear fit:**

$R_{\text{int}}$  = inverse of the slope

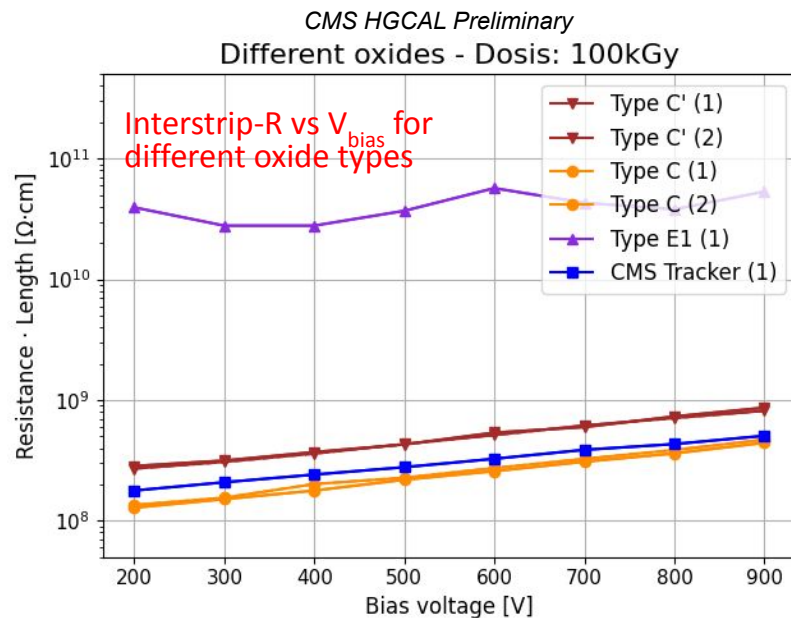
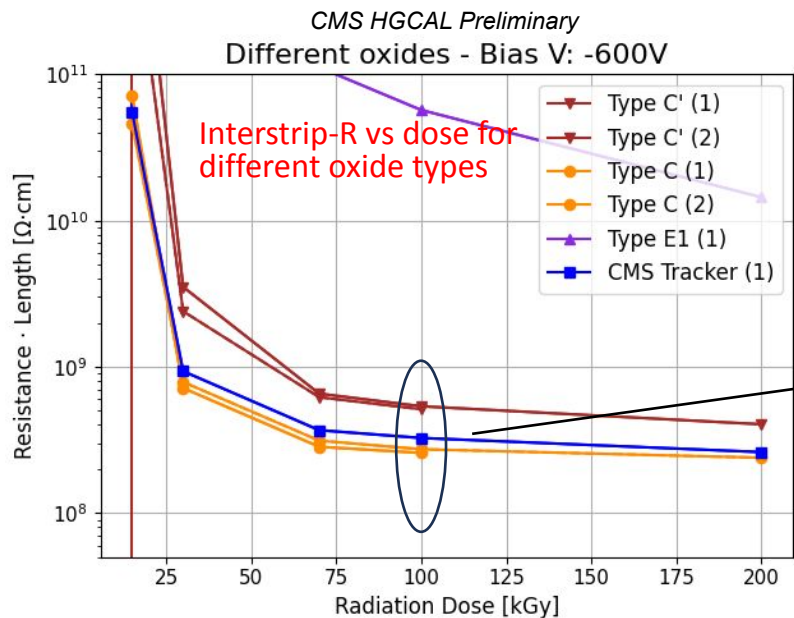
$I_{\text{leak}}$  = intercept

Interstrip current vs interstrip voltage curves for a C-prime 300 $\mu\text{m}$  sensor using a fixed radiation dose and different bias voltages (left) and fixed bias voltage and different radiation doses (right). The dashed line corresponds to the linear fit.



For small irradiation doses (and low bias voltages) we observe that the behaviour is not linear

-> we will adopt an ad-hoc solution for this, or discard the dose point



- Around **x2** higher R for **Type C'** when compare to **Type C** in line with higher initial p-stop concentration
- Around **x100** higher R for **Type E1** due to the higher concentration of p-stops

Trends vs dose and V are **similar between type C and C'** => **no clear preference** between the two



# Summary



- **Goal:** Identify best oxide process for HGICAL production silicon sensors
- Investigation of **oxide radiation damage** as a function of the absorbed dose
- In-situ measurement procedure allows to obtain **excellent reproducibility** of the result
  
- Comparison of production process candidates **Type C** and **Type C'**
  - MOS irradiation (floating and biased)
    - No clear difference
  - Inter-strip resistance
    - Not directly comparable because of different p-stop
    - Same rate of degradation as a function of the dose -> no clear preference
  
- Production of HGICAL silicon sensors had started with **Type C** before the studies were completed
- No practical advantage to moving to **Type C'** from **Type C**, considering
  - More extensive qualification of **Type C** at HPK and in CMS (e.g. pre-production)
  - Decided to stick to **Type C** for the rest of the HGICAL production
- **Type C'** interesting candidate for future silicon detector projects using 8-inch p-type sensors

# BACKUP

- Radiation damage in silicon oxide creates charge accumulation in border region + recombination current at the  $\text{Si-SiO}_2$  interface
- This favours the formation of an electron accumulation layer (n) that degrades the isolation properties between neighbouring cells (n+ implants)
  - partially mitigated by dedicated p-stop implants
- These effects can be studied using dedicated test structures with MOS and micro-strip sensors (see next slides)

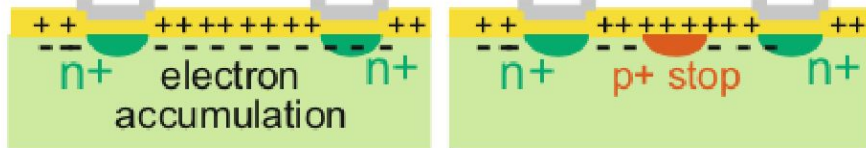
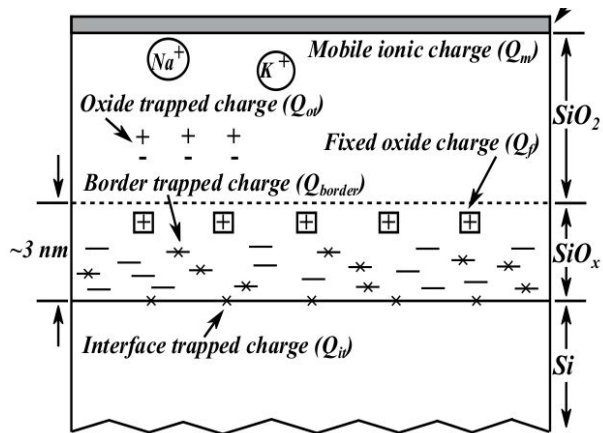
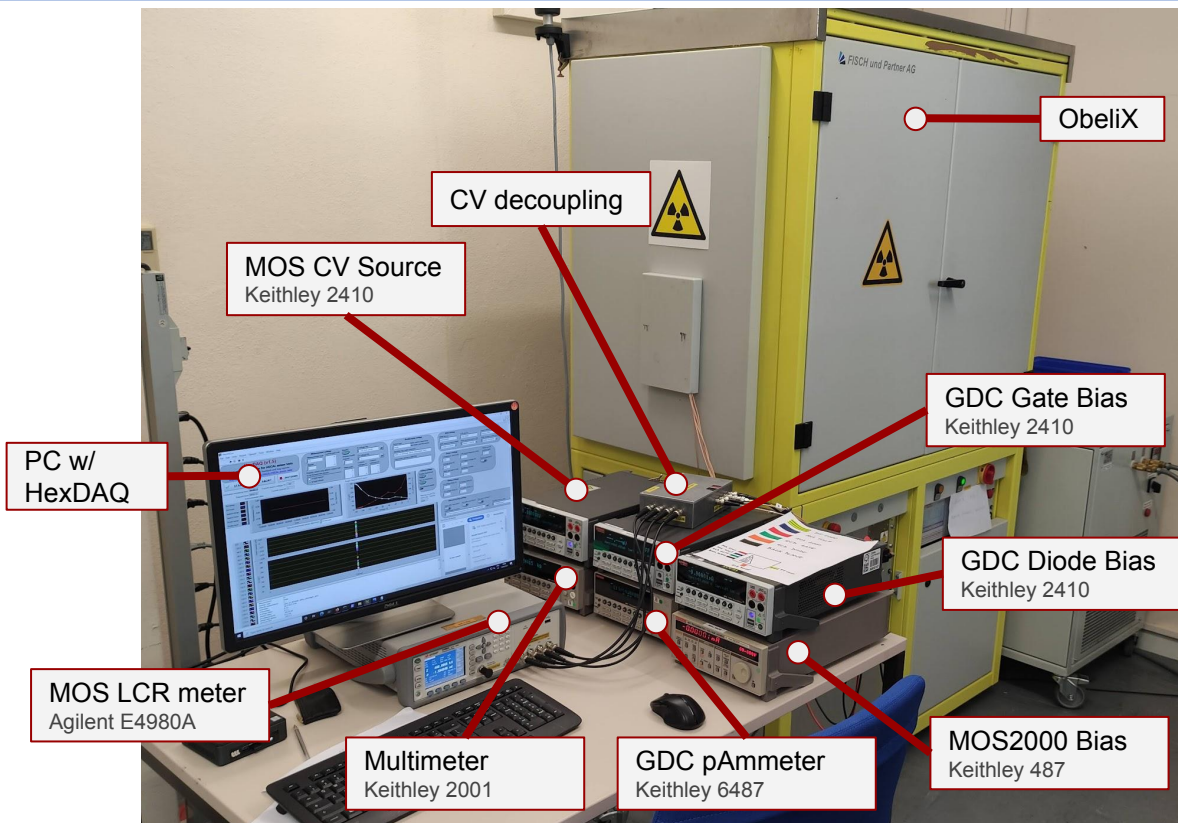
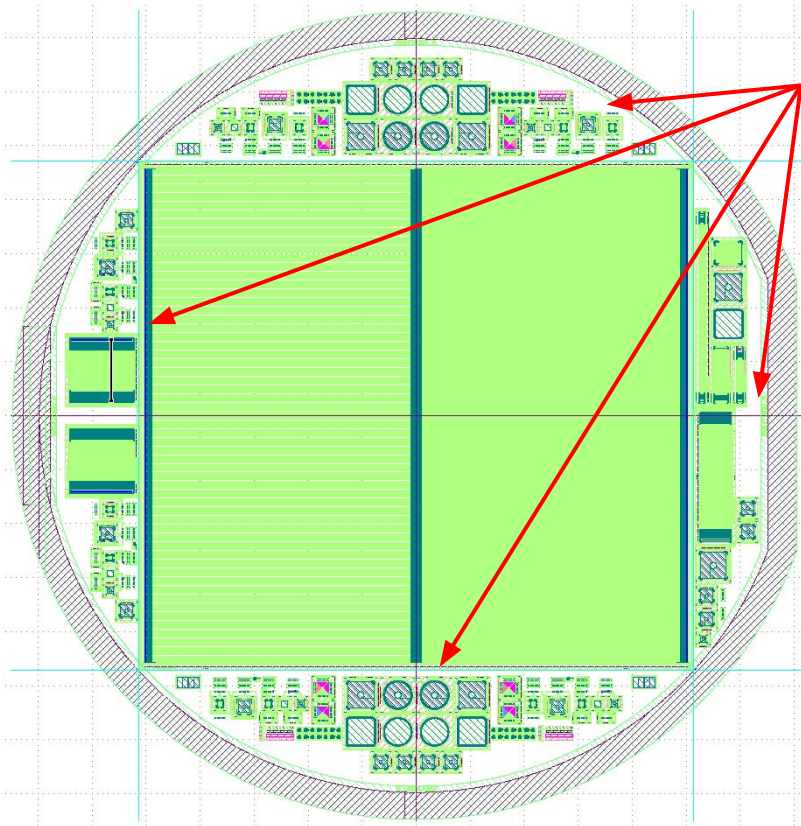


Illustration by Jan-Ole Müller-Gosewisch (KIT)

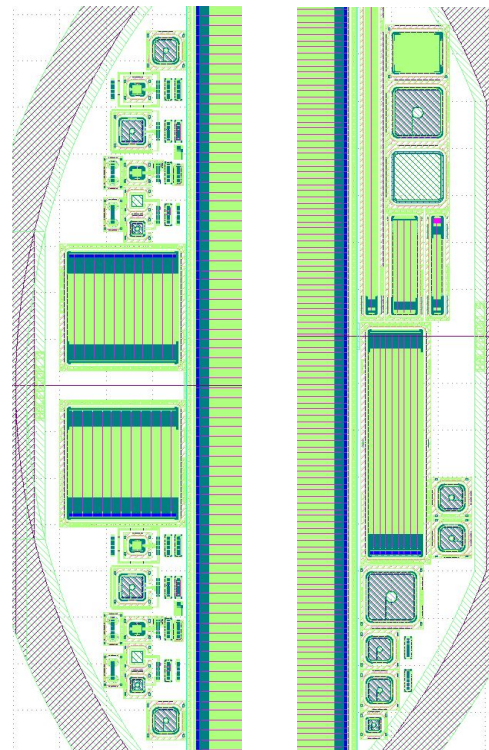
As a function of the absorbed dose, we therefore expect a degradation of the isolation between neighbouring strips, and an increase in the accumulated charge in the  $\text{SiO}_2$





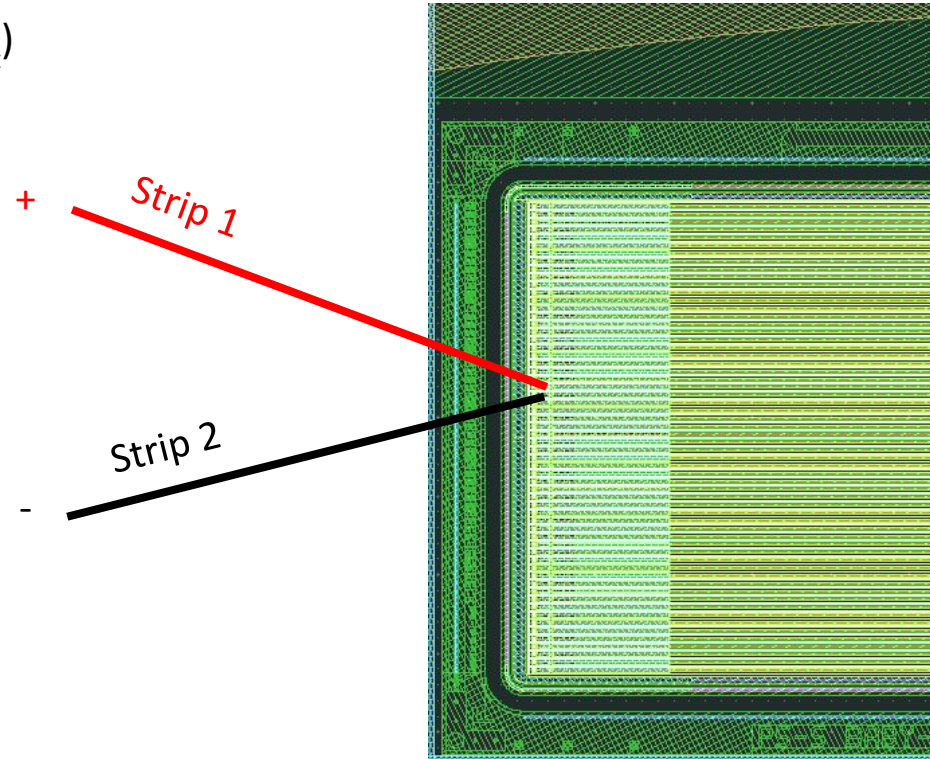
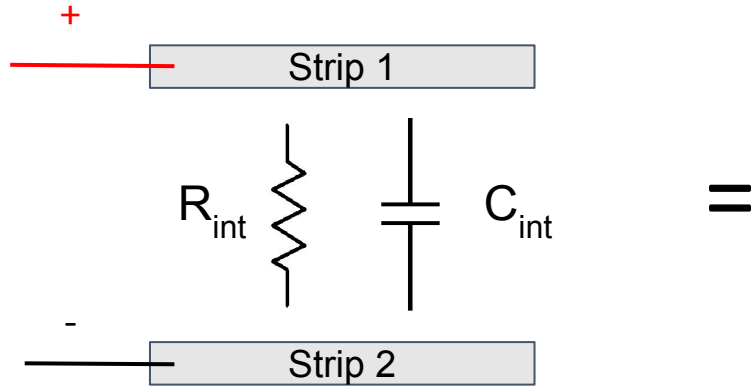


Test structures

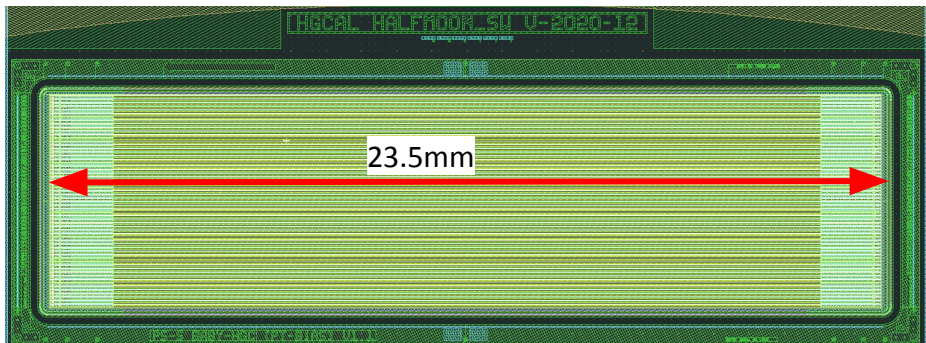


Close-up view

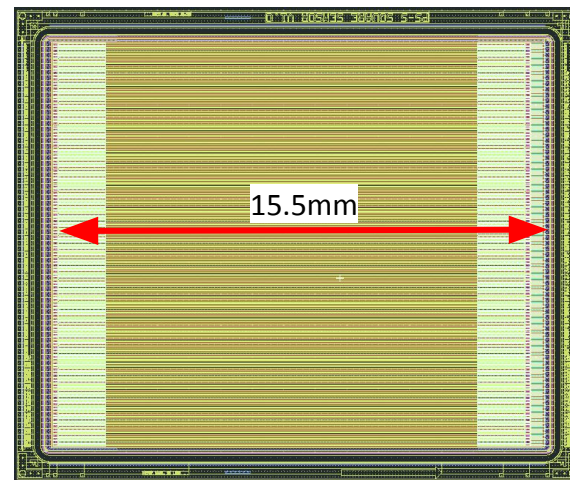
Interstrip Resistance ( $R_{int}$ ) and Capacitance ( $C_{int}$ )



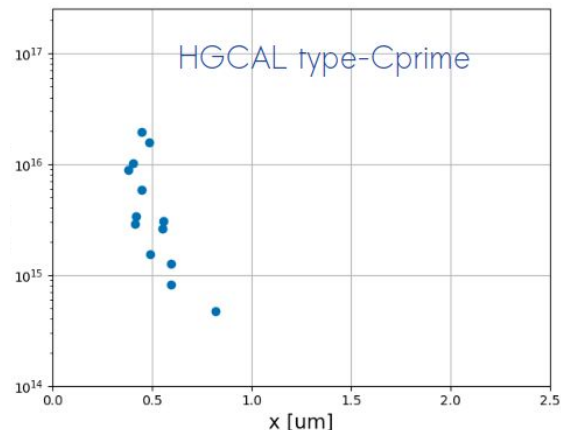
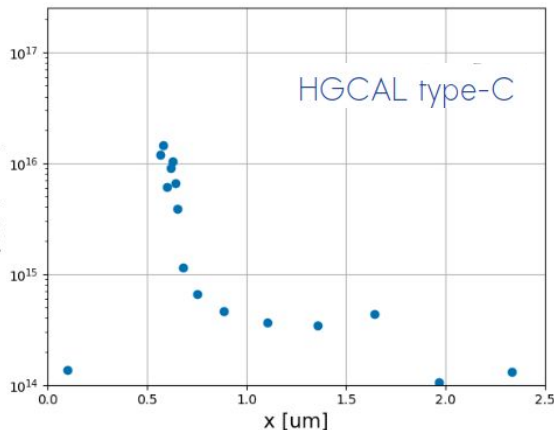
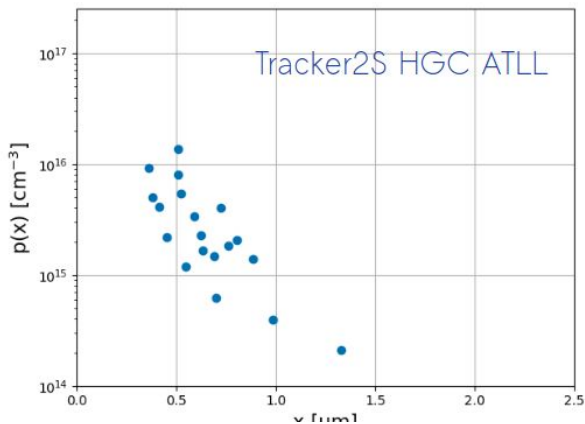
**HGCAL** tracker-like strip sensor:  
100 $\mu$ m pitch,  $\sim$ 23.5mm strip length, 60 strips



**Tracker** strip sensor test structure  
100 $\mu$ m pitch,  $\sim$ 15.5mm strip length, 128 strips



- Current flow is **perpendicular** to strip length
- Geometric normalization of results by accounting only for the **strip length**:
  - Resistance  $\cdot$  Length
  - Capacitance / Length



P-stop studies conducted by Thomas Bergauer, Suman Chatterjee, Marko Dragicovic, Kostas Damanakis, Ioannis Kopsalis, Veronika Kraus (HEPHY)

- Higher doping concentration observed for **Type C'** compared to **Type C**
- Slightly smaller concentration for **CMS Tracker** than for **Type C'**

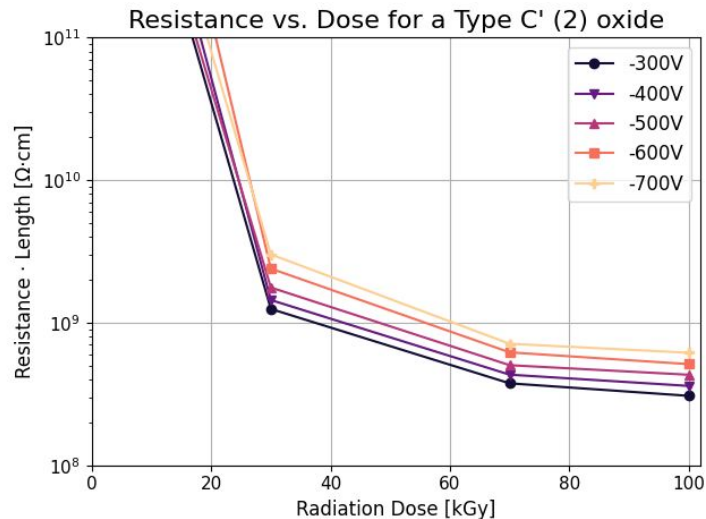
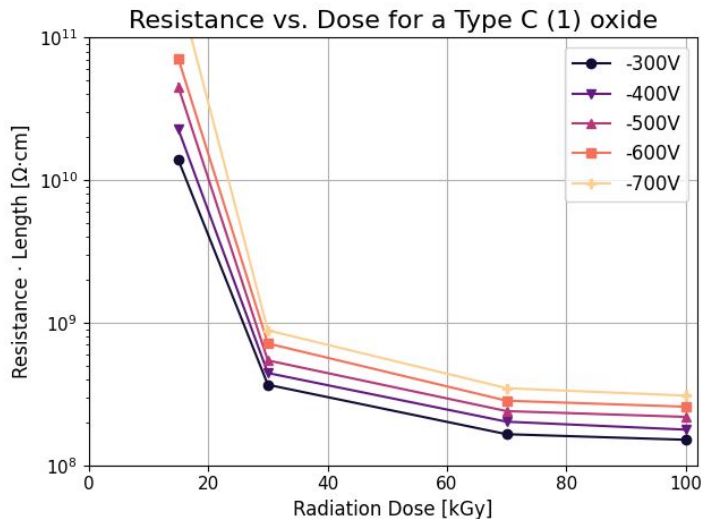
*Expected results:* ↑ **p-stop** concentration ⇒ ↑ **Resistance**



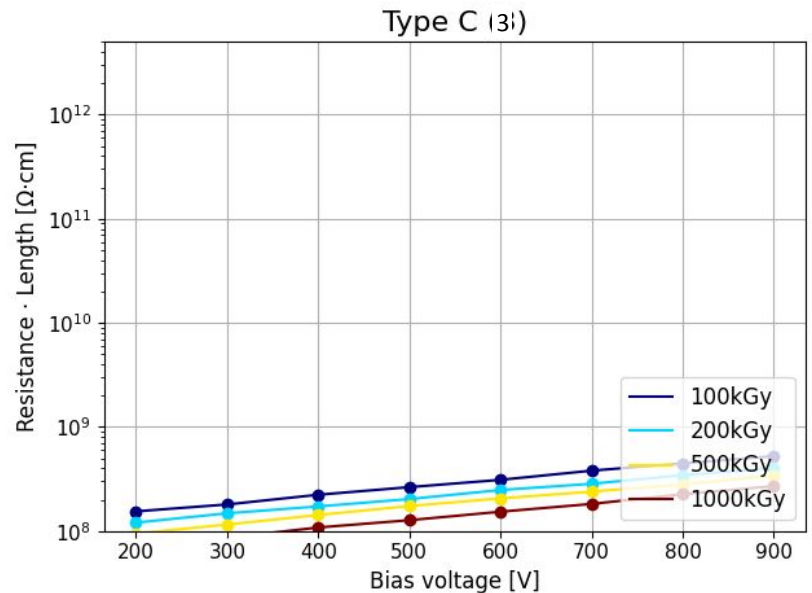
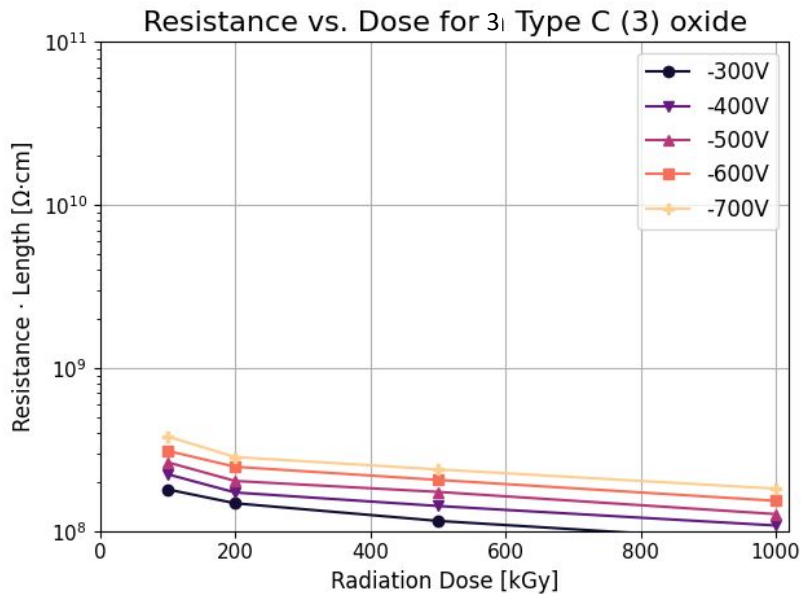
# Preliminary results: Interstrip-R vs dose (vs $V_{\text{bias}}$ )



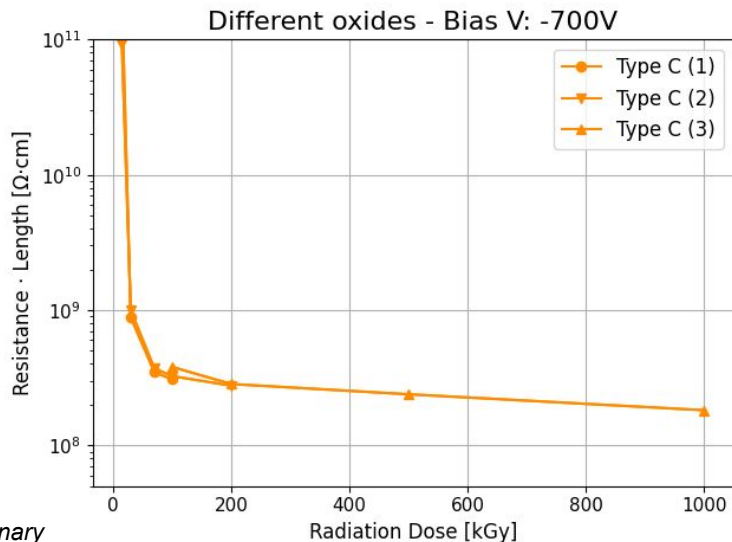
CMS HGAL Preliminary



Interstrip resistance vs radiation dose for type C (left) and C-prime (right) 300 $\mu\text{m}$  sensor using different bias voltages above full depletion



- Measured  $R_{int}$  well above the  $10^8 \Omega$  benchmark for  $V_{bias} > 400 \text{ V}$  at 1 MGy



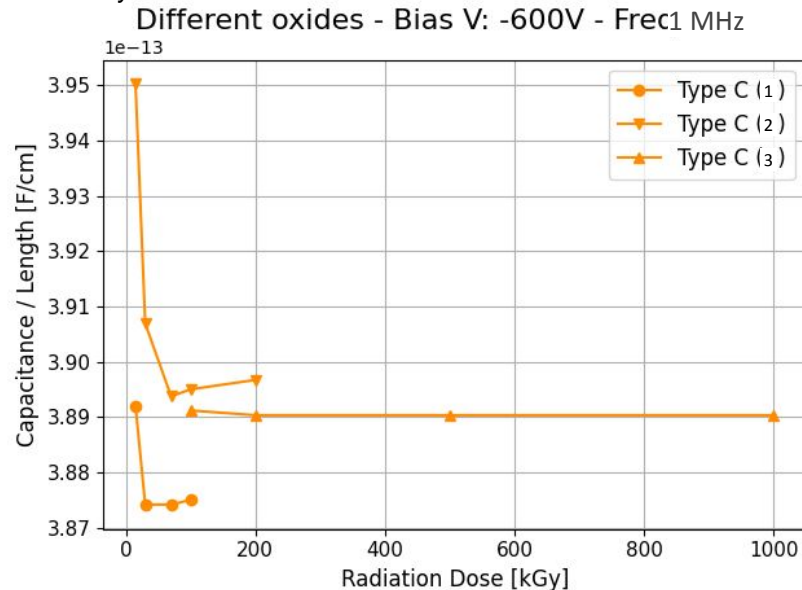
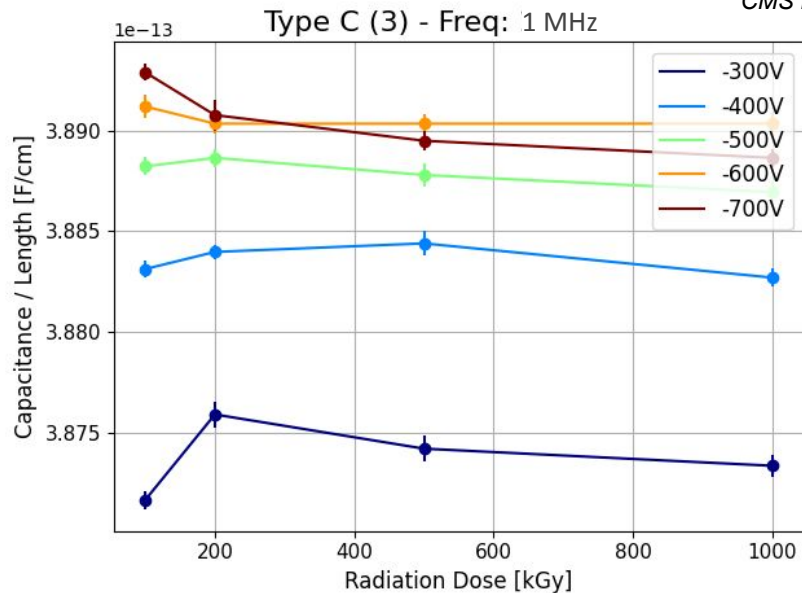
CMS HGICAL Preliminary

Attention:  
Different dose rates  
used (24.3kGy/h for  
1MGy vs 14.3kGy/h)

See slide 8

- Measured  $R_{int}$  well above the  $10^8 \Omega$  benchmark for  $V_{bias} > 400 \text{ V}$  at 1 MGy

CMS HGICAL Preliminary

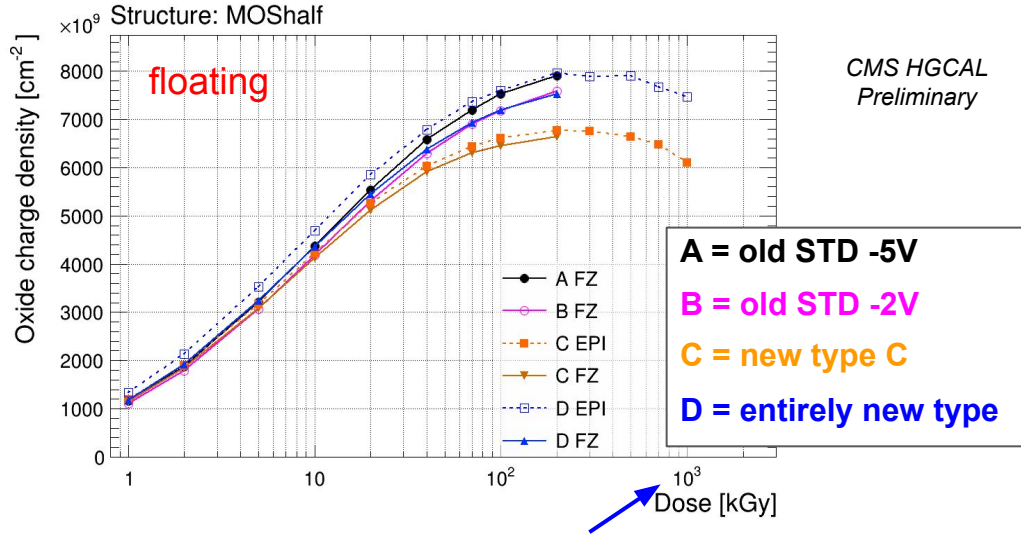


- Measured  $C_{int}$  almost constant for large values of radiation dose (**no degradation observed**)
- Consistent results within 1% between short and long irradiation campaigns

Attention: Different dose rates used  
(24.3kGy/h for 1MGy vs 14.3kGy/h)  
See slide 8



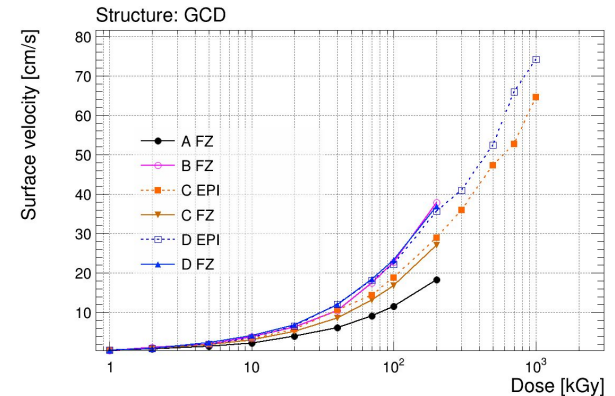
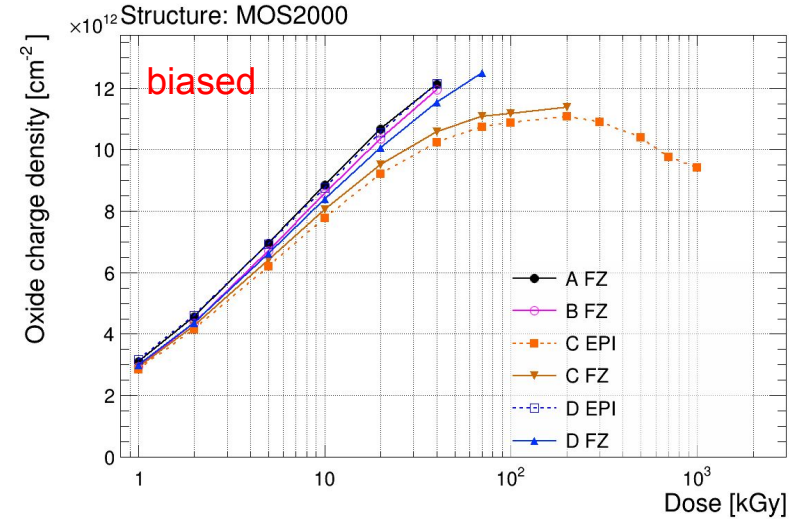
# MOS: Results for new types A-D



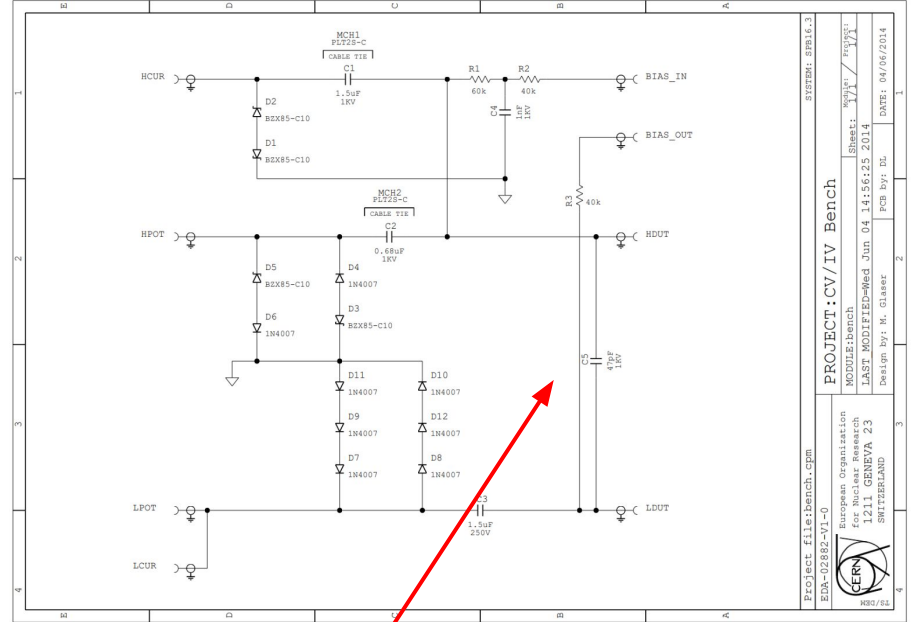
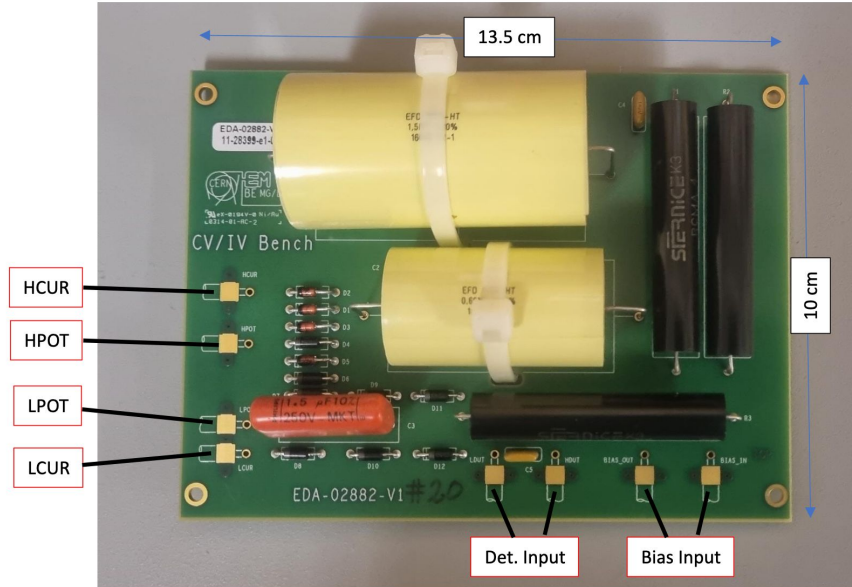
EPI material irradiated up to 1MGy (expected dose in forward region of the calorimeter at the end of HL-LHC)

confirmed preference for new type C -> currently being used by HPK for sensors production

-> new variant called C-prime recently provided by HPK



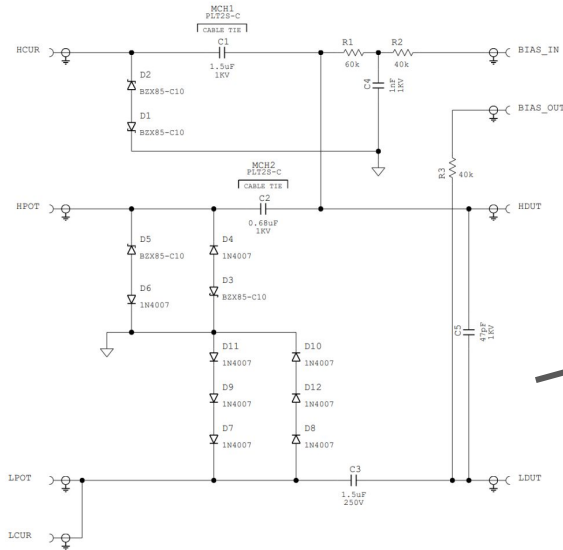
# Open correction for $C_{int}$



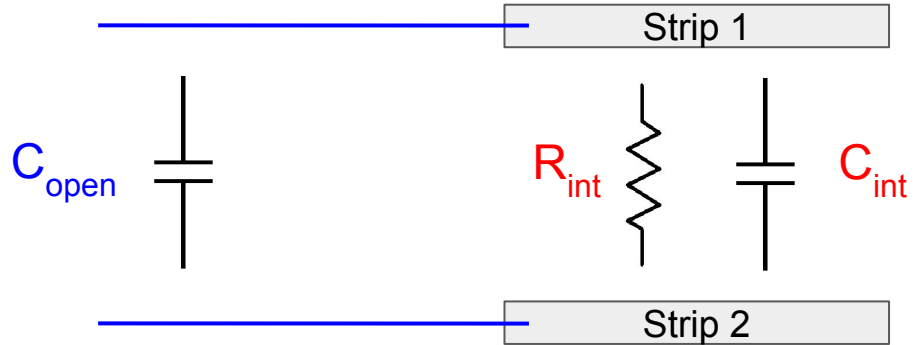
Open capacitance driven by  $C_5 = 47$  pF in decoupling box connected to LCR meter

Project file: Bench.cpm	SYSTEM: SFB16.3
EDA-02882-V1-0	PROJECT: CV/IV Bench
European Organization for Nuclear Research	MODULE: Bench
1211 GENEVA 23	Sheet: 001/01 / 001/01
SWITZERLAND	LAST MODIFIED: Wed Jun 04 14:56:23 2014
	Design by: M. Glaeser
	PCB by: DL
	DATE: 04/06/2014

# Open correction for $C_{int}$



$$C_{corr} = C_{meas} - C_{open}$$



- Measured  $C_{open} = 49.7$  pF (consistent with  $C_5 = 47$  pF of design sheet)
- Simplified correction  $C_{corr} = C_{meas} - C_{open}$
- Open correction derived for each LCR frequency

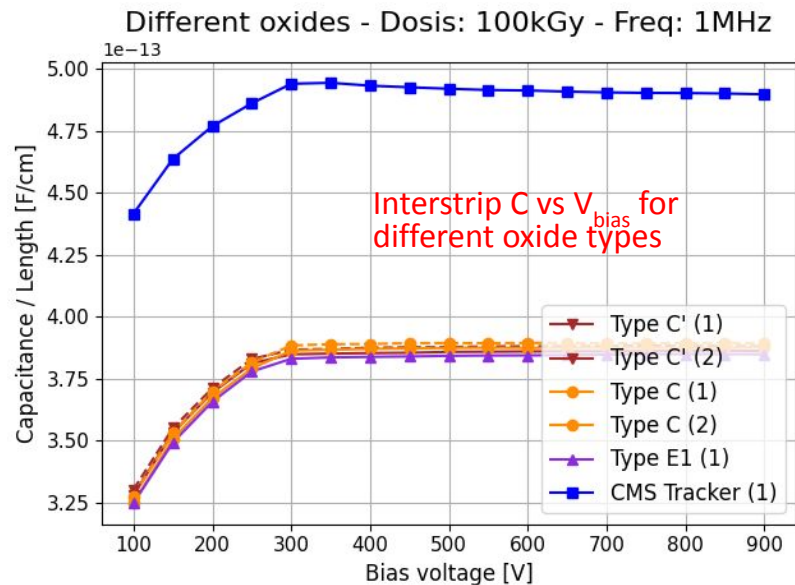
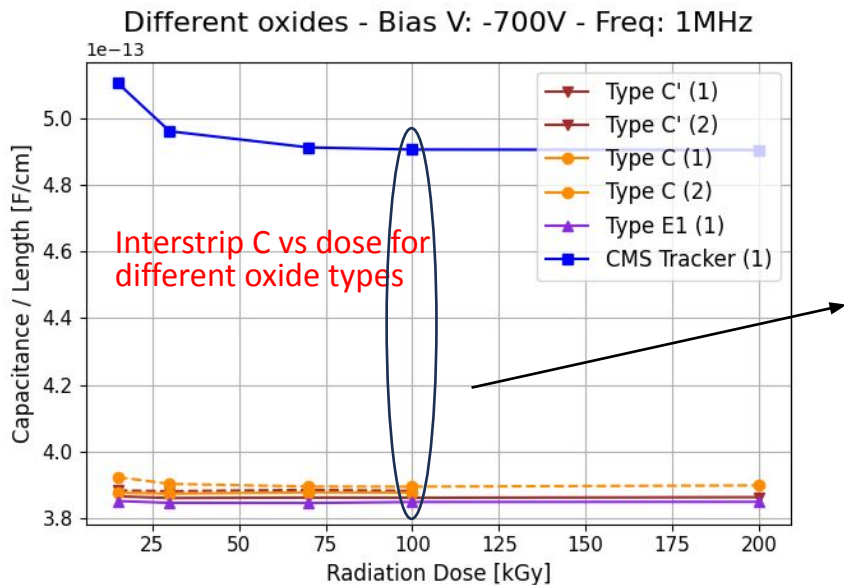


# Summary including CMS Tracker



Comparison of production process candidates **Type C**, **Type C'** and **CMS tracker**

- MOS irradiation (floating and biased)
  - **Comparable results** in **MOS** measurements for all oxides
- Inter-strip resistance
  - **Slightly higher inter-strip resistance for Type C'** compared to **Type C**. **CMS tracker** very similar to **Type C**.
- Inter-strip capacitance
  - **Lower inter-strip capacitance in type C and C'** compared to **CMS tracker sensors**



- Same performance of **Type C, C' and E1** (differences smaller than 1%, which is the same order of magnitude of the measurement reproducibility)
- **CMS Tracker** offered a capacitance around **30% larger**



# Samples of strip sensors



	Copies	Maximum dose [kGy]	Comment
<b>Type C</b>	"(1), (2)" "(3)"	200@14.3kGy/h 1000@24.3kGy/h	Production sensors so far
<b>Type C'</b>	"(1), (2)"	200@14.3kGy/h	Proposed by HPK, closer to tracker, higher p-stop concentration than Type C
<b>Type E1</b>	"(1)"	200@14.3kGy/h	Type C with 2.5x p-stop concentration
<b>CMS outer tracker</b>	"(1)"	200@14.3kGy/h	

## HGCAL:

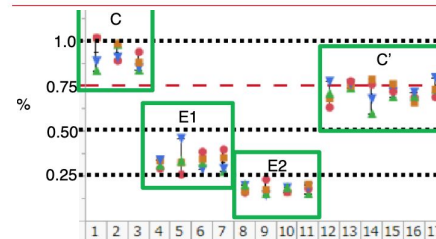
- all 300 $\mu$ m float zone (FZ),  $V_{dep} = \sim 270V$

## CMS outer tracker:

- Sample from PS-s wafer from the pre-production (series S15569-01)
- 320 $\mu$ m physical thickness, 290 $\mu$ m active thickness, deep diffused float zone (dd-FZ)

230314 300 $\mu$ m	Vfb	p-stop	oxide quality improvement	p-stop concentration	comment
A	-5V	common	STD	STD	not improved Vfb & STD condition (for ref.)
B	-2V	common	STD	STD	improved Vfb with special masking method
C	-2V	common	thermal condition change	STD	(for ref.) production condition
C'	-2V	common	thermal condition change	STD	more close to 6" line than type C
D	-2V	common	combination of B and C	STD	CMS required condition
E1	-2V	common	thermal condition change	x2.5	combination C and p-stop concentration
E2	-2V	common	thermal condition change	x5.0	

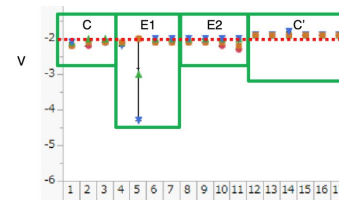
## P-stop resistance for each condition



Type C' is about 20% lower than type C.



## Flatband voltage for each condition



The flatband voltage of type C' is nearer to 0V than that of type C. However, there is no difference and oxide layer quality is almost same we think. Productivity for type C' is also same level as type C.

